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		Application Number	New A	pplication 10/100119		
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		First Named Inventor	Tatsuy	a HONDA		
		Art Unit		2825		
		Examiner Name		PAUL DINH		
Sheet	1	of	1	Attorney Docket Number	740756	5-2664
				U.S. PATENT DOCUMEN	its	
Examiner	Cite	U.S. Patent Do	cument	D. Mineries Davis	N- CD	Pages Columns Lines Where

Examiner Initials*	Cite No. ¹	U.S. Patent Document Number - Kind Code ² (if known)	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columna, Lines, Where Relevant Passages or Relevant Figures Appear
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			FOREIGN PATENT	DOCUMENTS		
Examiner Initials*	Cite No. ¹	Foreign Patent Document Kind Code Country Code ³ Number ⁴ (if known)		Name of Patentee or Application of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ^e
PD		JP 07-66258	03/10/1995	Kataoka et al.		Abstract
		OTHER PRIC	R ART – NON PATENT	LITERATURE DOCUMENTS		
Examiner Initials	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.)., date, page(s), volume-issue number(s), publisher, city and/or country where published.				T²
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PD		C.J. KANG et al., "Charg microscopy", Applied Ph				

Examiner Signature	Paul	Din	Date Considered	4/4/06

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